CS99-065



July 11, 2001

To: Commissioner of Patents and Trademarks

Washington, D.C. 20231

Fr: George O. Saile

Reg. No. 19,572

20 McIntosh Drive

Poughkeepsie, N.Y. 12603

Re:

Serial No. 09/442,499

Filed: 11/18/99

Invr: Ho, P.K., et al

Title: Plasma Etch Method for Forming Plasma Etched Silicon Layer

Examiner: Goudreau, B. Art Unit: 1763

TC 1700 MAIL ROOM

ASSOCIATE POWER OF ATTORNEY

Dear Sir:

I hereby appoint Stephen G. Stanton, registration number 35,690, as my associate attorney in this case. His telephone number is (610) 296-5194.

Please continue to direct all correspondence in this case to George O. Saile.

George Ø. Saile, Reg. No. 19,572

Principal Attorney of Record

bectfully submit